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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE
(Case No. 207.010-US)

In the Application of: **LUTZ ET AL.**

Serial No: **10/698,268**

Filed: **OCTOBER 31, 2003**

Title: **ANTI-STICTION TECHNIQUE FOR THIN FILM
AND WAFER-BONDED ENCAPSULATED
MICROELECTROMECHANICAL SYSTEMS**

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

)
) Group
) Art Unit: **2814**
)
) Before
) Examiner

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail with sufficient postage in an envelope addressed to the Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on June 10, 2004

Michiko Sides ^{Date}
(person signing this certificate)

Michiko Sides
Signature

SECOND INFORMATION DISCLOSURE STATEMENT

Dear Sir:

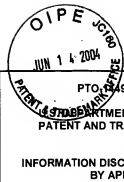
Submitted herewith is one (1) sheets of a modified Form PTO-1449. A copy of each document cited on the attached Form PTO-1449 is also submitted.

It is respectfully requested that the Examiner make his/her consideration of these documents formally of record with the initial Office Action.

Respectfully submitted,

Date: June 10, 2004

Neil A. Steinberg
Reg. No. 34,735
650-968-8079



Sheet 1 of 1

PTO 649 (Modified) DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE INFORMATION DISCLOSURE STATEMENT BY APPLICANT	ATTY. DOCKET NO. 207.010-US	SERIAL NUMBER 10/698,258
	APPLICANT(S) Lutz et al.	
	FILING DATE October 31, 2003	GROUP ART UNIT 2814

U.S. PATENT DOCUMENTS

EXAMINER INITIALS	DOCUMENT NUMBER	DATE	NAME	CLAS S	SUB CLAS S	FILING DATE
	4,849,071	7/1989	Evans et al.			
	4,945,769	8/1990	Sidner et al.			
	5,445,991	8/1995	Lee			
	5,470,797	11/1995	Mastrangelo			
	5,616,514	4/1997	Muchow et al.			
	6,521,508	2/2003	Cheong et al.			

FOREIGN PATENT DOCUMENTS

EXAMINER INITIALS	DOCUMENT NUMBER	DATE	COUNTRY	CLAS S	SUB CLAS S	TRANSLATION YES/NO

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

"Chemical Vapor Deposition of Fluoroalkylsilane Monolayer Films for Adhesion Control in Microelectromechanical Systems", Mayer et al., J. Vac. Sci. Technol. B 18(5), Sept/Oct 2000, pp.2433-2440

EXAMINER	DATE CONSIDERED
EXAMINER: Initial citation if reference was considered. Draw line through citation if not in conformance to MPEP 609 and not considered. Include copy of this form with next communication to applicant.	